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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

Complete if Known	
Application Number	~~Unknown~~ 10/677,057
Filing Date	Even Date Herewith 9/30/03
First Named Inventor	Juengling, Werner
Group Art Unit	~~Unknown~~ 2891
Examiner Name	~~Kilday, Lisa~~ THAI, LUAN

Sheet 1 of 1

Attorney Docket No: 303.510US2

US PATENT DOCUMENTS

Examiner Initial *	USP Document Number	Publication Date	Name of Patentee or Applicant of cited Document	Class	Subclass	Filing Date If Appropriate
LT	US-5,518,959	05/21/1996	Jang, S. , et al.	437	190	08/24/1995
	US-5,776,834	07/07/1998	Avanzino, S. , et al.	438	692	06/07/1995
	US-5,814,555	09/29/1998	Bandyopadhyay, B. , et al.	438	619	06/05/1996
	US-5,858,876	01/12/1999	Chew, P.	438	695	04/01/1996
	US-5,872,058	02/16/1999	Van Cleemput, P. A., et al.	438	692	06/17/1997
	US-6,030,881	02/29/2000	Papsouliotis, G. D., et al.	438	424	05/05/1998
	US-6,207,571	03/27/2001	Juengling, W. , et al.	438	692	03/01/1900
LT	US-6,223,331	04/24/2001	Juengling, W.	716	10	07/30/1998

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Foreign Document No	Publication Date	Name of Patentee or Applicant of cited Document	Class	Subclass	T[2]
LT	EP-0766291	04/02/1997	Nag, S. S., et al.	H01L	21/314	

OTHER DOCUMENTS -- NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No [1]	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T[2]
LT		"Chemical Vapor Deposition", Trikon Technologies, http://www.trikon.com/trikon/html/cvd.html,(1999),pp. 1-5	
LT		STINE, B. E., et al., "The Physical and Electrical Effects of Metal-Fill Patterning Practices for Oxide Chemical-Mechanical Polishing Processes", IEEE Transactions on Electron Devices, 45(3), (1998),pp . 665-679	
LT		WOLF, S. , Silicon Processing for the VLSI Era, Volume 2: Process Integration, Lattice Press, Sunset Beach, California, ISBN 0-961672-4-5,(1990),pp. 176-297	

EXAMINER [signature] DATE CONSIDERED 10/15/05

Substitute Disclosure Statement Form (PTO-1449)

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